

3600.0881-D5  
February 12, 2001 (1:25PM)



Docket: AM-0881.D5

*V. Douglas*  
*#6 / Pre*  
*Amend*  
*A*  
*2/23/01*

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:** Robert D. Tolles et al.

**Attorneys Docket:** AM-0881.D5

**Serial No.:** 09/507,172

**Art Unit No.:** 3723

**Filed:** February 18, 2000

**Examiner:** unknown

**For:** "CHEMICAL MECHANICAL POLISHING SYSTEM HAVING MULTIPLE POLISHING STATIONS AND PROVIDING RELATIVE LINEAR POLISHING MOTION"

Commissioner of Patents and Trademarks  
Washington, DC 20231

**AMENDMENT UNDER 37 CFR §1.115**

Sir:

In a Preliminary Amendment for consideration before initial examination, please amend the above application as follows:

**In the claims:**

*Sub B1*  
*a1*

1. (Amended) A polishing apparatus, comprising:  
a rotatable member rotatable about a first axis;  
at least two polishing surfaces arranged at respective angular positions about said first axis;  
at least one substrate head assembly supported on said rotatable member and capable of supporting [holding] thereon a substrate in contact with a selected one of said polishing surfaces and affording relative linear movement between said selected polishing surface and said substrate head assembly while said substrate supported on [held by] said substrate head is engaged with said selected polishing surface.

02/23/2001 AGOITOM 00000111 09507172

01 FC:103  
02 FC:102

198.00 OP  
240.00 OP